

RF Probe Station – Vervier RF6T

DATA SHEET

RF6T

The RF6T is an stable and extremely precise RF probe station built for research R&D and university lab probing use. It is available in 100mm (4") and 150mm (6") Chuck stage. Vervier RF6T is to be designed to assist RD specialist to characterize MMIC or DC measurement in manual conditions.

The of probe systems is specifically designed to address the requirements of research personnel - simplicity and ease of operation, portability, affordability and modularity. The Vervier RF6T provides features and options such as High magnification optical output scope, Optical device probing, multi-die DC characterization probing, Low-leakage/High Voltage probing. Customer can easily choose numerous accessories can be added at a later date to enhance the system functionality.



FEATURES AND BENEFITS

- Firm footprint – fits on a desk, small bench, in a glove box or dark box
- Sold as a completely configured system
- Interchangeable components - can be used as a single or multiple application system
- Modular – numerous accessories can be added for additional capability
- DC, RF/Microwave versions available

CONFIGURATION INCLUDES:

- Rigid Stainless Steel base on Aluminium Alloy structure design
- Coarse and fine wafer stage adjustment with interchangeable stage options - packaged part or thermal
- Fine stage movement using precision micrometer control - X (24 mm), Y (24 mm) & Z (>28 mm)
- Coarse (360 degrees) and fine (10 degrees) theta adjustment
- 150 mm (6") chuck with isolation adapter and vacuum control system
- Stainless steel plated platen with removable front wedge
- Two (2) RF PSTRF400 manipulators with magnetic bases, face plates and coaxial probe arms (standard)
- Microscope post with coaxial and linear microscope X, Y movement of 75 mm x 50 mm
- 40X~230X or 55X~300X magnification single lens microscope with 160 mm working distance

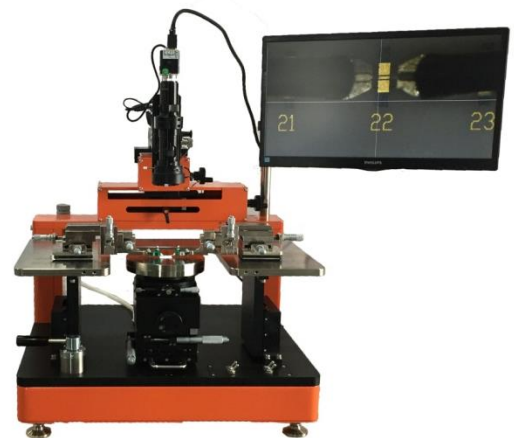
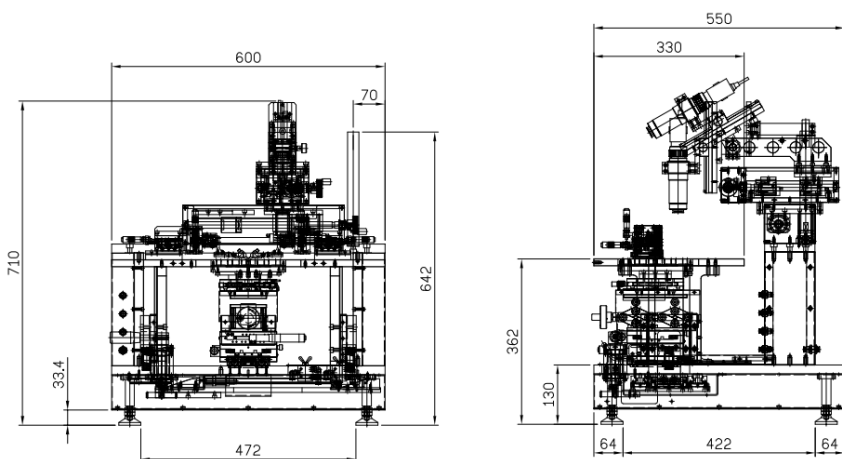


SPECIFICATIONS

Dimensions	600 mm X 710 mm X 550 mm (23.6" X 27.9" X 21.6") (W,H,L) – with Optics
Weight	90 kg (198 lbs.)
Base	Solid Aluminum Alloy rigid base on universal joints foot
Chuck Stage X-Y Movement	Fine micrometer adjustment – 24 mm (X, Y)
Chuck Stage Z Movement	Z travel: 28 mm (1.1") with micrometer driven contact/separation
Theta Movement	Travel: 360 degrees (coarse) and 10 degrees (fine) with theta locking knob
Chucks	Vacuum or mechanical clamping, round or square, HF, ambient, thermal and custom Handle die, waffle packs, sawn wafers on frame, broken wafers and wafers up to 150 mm Nickel plated steel with concentric vacuum rings (standard), Porous ceramic, other materials available
Platen	Aluminum with stainless steel top and removable front wedge for easy wafer handling Manipulator – magnetic (standard), vacuum (with optional vacuum manifolds)
Platen Movement	Two-level setting: height 0-30mm(Z)
Microscope Movement	Manual coaxial and linear fine microscope movement - 75 mm (X) and 50 mm (Y) (3"x2")
Optics	40X~230X or 55X~300X magnification single lens microscope
Utilities	150 mm working distance Power: AC 110V AC 50-60 Hz 20A Vacuum: 23 Hg or -0.8 bar
Options & Accessories	CCD Systems (camera, monitor and adapter) and stand (shown in picture page 1) Manipulators, Probe Arms, Probes, Cables – Coaxial, Triaxial, HF, Optical Probe Card and Package Part Holders Vibration Isolation Tables, Dark Box Stages – wafer, packaged part, thermal

Note: Data and specifications vary depending on probe system configurations and accessories

DIMENSIONS



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